

## **AMENDMENTS TO THE CLAIMS**

The following listing of claims will replace all prior versions and listings of claims in the application.

### **LISTING OF CLAIMS**

1. (currently amended) A method for fabricating an inkjet head comprising a plurality of piezoelectric elements, each having a first electrode layer, a piezoelectric layer, a second electrode layer and an oscillation layer, for pressurizing ink contained in a plurality of ink chambers to discharge the ink to a recording medium from a plurality of nozzles communicated with the respective ink chambers, the method characterized by comprising the steps of:

sequentially forming the first electrode layer, the piezoelectric layer, the second electrode layer and the oscillation layer over one surface of a substrate;

forming, on the oscillation layer, an ink chamber partition for separating the plurality of ink chambers from each other;

forming, on the ink chamber partition, a nozzle plate provided with the plurality of nozzles, thereby defining the plurality of ink chambers;

after the ink chamber partition forming step, mechanically grinding away a part of the substrate from a surface thereof opposite to the first electrode layer;

after the grinding away step, etching away a remnant substrate; and

after the etching away step, patterning at least the first electrode layer so that its ~~position~~ a position of the first electrode layer corresponds to that of an associated one of the ink chambers, thereby forming the plurality of piezoelectric elements.

2. (original) The inkjet head fabricating method according to Claim 1, the method characterized in that:

the first electrode layer comprises at least one of Pt, Ir, Pd, Au, Ni, Fe, Cu and Cr; and

in the etching away step, the remnant substrate is dry etched away.